



INDIAN INSTITUTE OF TECHNOLOGY BOMBAY

MATERIALS MANAGEMENT DIVISION

Powai, Mumbai - 400076

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Technical Specification of Spare Part for Dual Chamber Sputtering System

Sr	Content	Oty	Compliance (Yes/No)
1	Sputtering Source A. Additional A320-XP-O low profile UHV magnetron sputtering sources with integral isolation chimneys, pneumatic UHV shutters, and individual gas injection capability via VCR port on cluster flange. Installation as the additional source on the chamber periphery in confocal orientation.	2	
2	One-year Warranty	--	